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ABSTRACT

A METHOD OF FABRICATING A SUBSTRATE, IN PARTICULAR FOR OPTICS, ELECTRONICS, OR OPTOELECTRONICS, AND A SUBSTRATE OBTAINED BY THE METHOD

The invention relates to a method of fabricating a substrate comprising a thin layer carried by a layer constituting a mechanical support, in particular for optics, electronics, or optoelectronics. According to the invention, the method comprises the following steps:

· detaching a layer of material for forming the thin layer (2) from a source substrate (6); and then

· making a thick layer (4) on the thin layer (2) by depositing material to form the layer which constitutes the mechanical support.



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